

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:) **CONFIRMATION NO.: 5022**
Seishi MURAKAMI, et al.)
U.S. Serial No.: 10/584,642) Group Art Unit: 1715
Filed: June 13, 2007) Examiner: Mandy C. Louie

For: FORMATION OF TITANIUM NITRIDE FILM

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed September 8, 2010 is due by October 8, 2010. The Action required restriction among four patentably distinct inventions.

Applicants hereby elect Group I of claims 1-9, 11-14, and 19-24, drawn to a method of vapor deposition, for examination in this application. Applicants advise that no change in the inventorship of the application will be required by the eventual cancellation of non-elected claims.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,
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